



Dated: 02.12.2022

Corrigendum-I

For (PR No.1000026924) RfX No.6100001226

**Electron Beam Evaporator**

Sr. No.	Online RfX Clause	Previous Clause	Changed Clause
1	Evaporation system is required for deposition of following materials	The system should include the main deposition chamber, a fast-entry load-lock, suitable transfer mechanism, necessary vacuum pumps, valves, gauges, electron guns, thermal sources, power supplies, substrate fixture with active cooling mechanism, shutters, instrumentation and all necessary controls (Please see details below). The system should be operable in semi-automatic or fully manual mode.	The system should include the main deposition chamber, a fast-entry load-lock, suitable transfer mechanism, necessary vacuum pumps, valves, gauges, electron guns, power supplies, substrate fixture with active cooling mechanism, shutters, instrumentation and all necessary controls (Please see details below). The system should be operable in semi-automatic or fully manual mode.
2	Electron beam sources	One Electron Beam Gun (EBG), procured from reputed manufacturers (Telemark, Temescal or equivalent), 6 number of 7-cc pockets, a rotatable hearth, programmable XY sweep control, and 2700 beam deflection option should be provided.	One Electron Beam Gun (EBG), procured from reputed manufacturers (Telemark, Temescal or equivalent), 8 number of 4-cc pockets, a rotatable hearth, programmable XY sweep control, and 270 <sup>0</sup> beamdeflection option should be provided.
3	Thermal sources	Two box-type thermal evaporation sources, rated for a maximum current of 400 A or more should be provided. The source should be capable of accommodating spirals, baskets, filament and tungsten boats of standard lengths. A digital programmable DC power supply, providing variable current of up to 200A should be provided.	<b><u>Clause Deleted</u></b>
4	Shutters for Sources	Necessary number of pneumatically controlled shutters should be provided separately for the electron-beam and thermal sources. It	Necessary number of pneumatically controlled shutters should be provided separately for the electron-beam

		should be possible to override the automatic mode and control the shutters in manual mode.	It should be possible to override the automatic mode and control theshutters in manual mode.
5	List of spares and accessories to be provided:  Accessories	A chiller of the appropriate capacity required for substrate cooling, boats (50) and spirals (10) for thermal evaporation source, quartzcrystal-sensor test kit, electron-source service kit.7cc crucible liners (Boron Nitride, Alumina, Graphite and Vitreous Carbon over Graphite) 2 Nos each.	A chiller of the appropriate capacity required for substrate cooling, quartz- crystal-sensor test kit, electron-source service kit.4cc crucible liners (Boron Nitride, Alumina, Graphite and Vitreous Carbon over Graphite) 2 Nos each.

Digital Signature  
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